

Application/Control No.	Applicant(s)/Patent under Reexamination		
10/825,109	CHEN, MEI-LI		
Examiner	Art Unit		
John Rivell	3753		

SEARCHED								
Class	Subclass	Date	Examiner					
137	625.17 625.4 625.41	7/10/2006	R					
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INTERFERENCE SEARCHED							
Subclass	Date	Examiner					
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)					
		DATE	EXMR		
None		7/11/2006	R		